

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	
Hidekazu MIYAIRI et al.)	Group Art Unit: 1722
Serial No. 10/663,671)	Examiner: Felisa Carla Hiteshew
Filed: September 17, 2003)	
For: LASER APPARATUS, LASER IRRADIATION METHOD, AND MANUFACTURING METHOD OF SEMICONDUCTOR DEVICE)	Date: January 11, 2006



RESPONSE TO REQUEST FOR RESTRICTION REQUIREMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Request for Restriction Response mailed December 12, 2005,
Applicants responds as follows: